IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.:	10/091,985	Confirmation No.:	6343
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Applicant(s): SUZUKI, et al. Group Art Unit: 2877

Examiner: Lee, Hwa S.

Filed: March 6, 2002

Customer No.: 27123

For: INTERFEROMETER AND INTERFERENCE MEASUREMENT METHOD

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Respectfully submitted, MORGAN & FINNEGAN, L.L.P.

Dated: June 20, 2007

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UNITED STATES PATENT AND TRADEMARK OFFICE SUPPLEMENTAL CERTIFICATE OF CORRECTION

PATENT NUMBER 7,106,455 B2

September 12, 2006 DATED

Akiyoshi SUZUKI, Yoshiyuki SEKINE INVENTOR(S)

It is certified that an error appears or errors appear in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

In the Title

INTERFEROMETER AND INTERFERANCE MEASUREMENT METHOD Replace "INTERFERANCE" with - INTERFERENCE --

ADDRESS ASSOCIATED WITH CUSTOMER NUMBER: 27123

PATENT NO.

7,106,455 B2

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(12) United States Patent Suzuki et al.

(10) Patent No.:

US 7,106,455 B2

(45) **Date of Patent:**

Sep. 12, 2006

(54) INTERFEROMETER AND INTERFERANCE MEASUREMENT METHOD

Inventors: Akiyoshi Suzuki, Tokyo (JP); Yoshiyuki Sekine, Tochigi (JP)

Assignee: Canon Kabushiki Kaisha, Tokyo (JP)

(*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 187 days.

(21) Appl. No.: 10/091,985

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Apr. 9, 2001	(JP)	***************************************	2001-109998

(51) Int. Cl. G01B 9/02

(2006.01)

(58) Field of Classification Search 356/512, 356/513, 521, 511; 378/36 See application file for complete search history.

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ABSTRACT

There is provided an interferometer for measuring a surface shape of an optical element using interference, including a reference wave-front generating unit for generating a reference wave front for measuring the surface shape, which is provided in a target optical path, and includes an Alvarez lens.

33 Claims, 10 Drawing Sheets

REFERENCE MIRROR

